



AF/IFW

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hou, Chien-Chou; et al.	)	Examiner:	Deo, Duy Vu Nguyen
Serial No.:	10/600,377	)	Art Unit:	1765
Filed:	June 20, 2003	)	Our Ref:	B-5130 621033-6
For:	"METHOD OF ETCHING UNIFORM SILICON LAYER"	)	Date:	August 23, 2006
		)	Re:	<i>Response to Final</i>

RESPONSE TO FINAL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is in reply to the final Office Action mailed on June 23, 2006, a response to which is due no later than

September 23, 2006.

Please consider the following remarks. **All remarks herein are made without prejudice**

**Remarks/Arguments** begin on Page 2 of this Response.